

IPW



Case Docket No. ASMJP.104DV1

Date: September 17, 2004

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s) : Akira SHIMIZU, et al.
 Appl. No. : 10/706,624
 Filed : November 12, 2003
 For : METHOD FOR
 SEMICONDUCTOR WAFER
 ETCHING
 Examiner : Mark H. Paschall
 Group Art Unit : 3742

I hereby certify that this correspondence and all marked attachments are being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on

September 17, 2004

(Date)

Katsuhiro Arai, Reg. No. 43,315

TRANSMITTAL LETTER

Commissioner for Patents
 P.O. Box 1450
 Alexandria, VA 22313-1450

Dear Sir:

Enclosed for filing in the above-identified application are:

- (X) An Information Disclosure Statement.
- (X) A PTO Form 1449 with ~~Substantive~~ references.
- (X) A copy of the communication from the European Patent Office.
- (X) The Commissioner is hereby authorized to charge any fees which may be required to Account No. 11-1410.
- (X) Return prepaid postcard.

Katsuhiro Arai
 Registration No. 43,315
 Attorney of Record
 Customer No. 20,995
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INFORMATION DISCLOSURE STATEMENT

Applicant : Akira SHIMIZU, et al.
App. No. : 10/706,624
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For : METHOD FOR SEMICONDUCTOR
WAFER ETCHING
Examiner : Mark H. Paschall
Group Art Unit : 3742

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Enclosed is form PTO-1449 listing ~~seven~~(7) references that are also enclosed.

This Information Disclosure Statement is being filed before the receipt of a first Office Action on the merits, and presumably no fee is required in accordance with 37 C.F.R. § 1.97(b)(3). If a first Office Action on the merits was mailed before the mailing date of this Statement, the Commissioner is authorized to charge the fee set forth in 37 C.F.R. § 1.17(p) to Deposit Account No. 11-1410.

Respectfully submitted,

KNOBBE, MARTENS, OLSON & BEAR, LLP

Dated: September 17, 2004

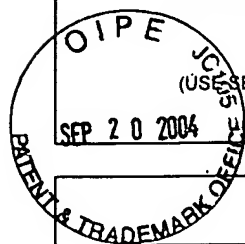
By: 

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FORM PTO-1449

U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICEATTY. DOCKET NO.
ASMJP.104DV1APPLICATION NO.
10/706,624INFORMATION DISCLOSURE STATEMENT
BY APPLICANT

(USE SEVERAL SHEETS IF NECESSARY)

APPLICANT
Akira SHIMIZU, et al.FILING DATE
November 12, 2003GROUP
1725

U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPROPRIATE)
	1.	4,804,431	02/14/89	Aaron RIBNER			
	2.	4,910,042	03/20/90	Jiri HOKYNAR			
	3.	5,023,056	06/11/91	Monti E. AKLUF1, et al.			
	4.	5,489,362	02/06/96	Heinz STEINHARDT, et al.			
	5.	5,795,831	08/18/98	Izumi NAKAYAMA, et al.			
	6.	5,954,911	09/21/99	Eric J. BERGMAN, et al.			

FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO

EXAMINER
INITIAL

OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)

	7.	D.F. Weston, et al. HF vapor phase etching (HF/VPE): Production viability for semiconductor manufacturing and reaction model, J. Vac. Scie. Technol., 17(1) Jan./Feb. 1980, 1980 American Vacuum Society, pp. 466-468.

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EXAMINER

DATE CONSIDERED

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